

# **Lecture 4 – Monolithic Microwave Integrated Circuits**

#### Review of Semiconductor Physics

Semiconductor materials, heterojunction and HEMT.

#### MMIC Manufacturing Technology

MMIC manufacturing process, foundry service.

#### MMIC Design Technology

Modeling and Process design kit, simulation and design software.

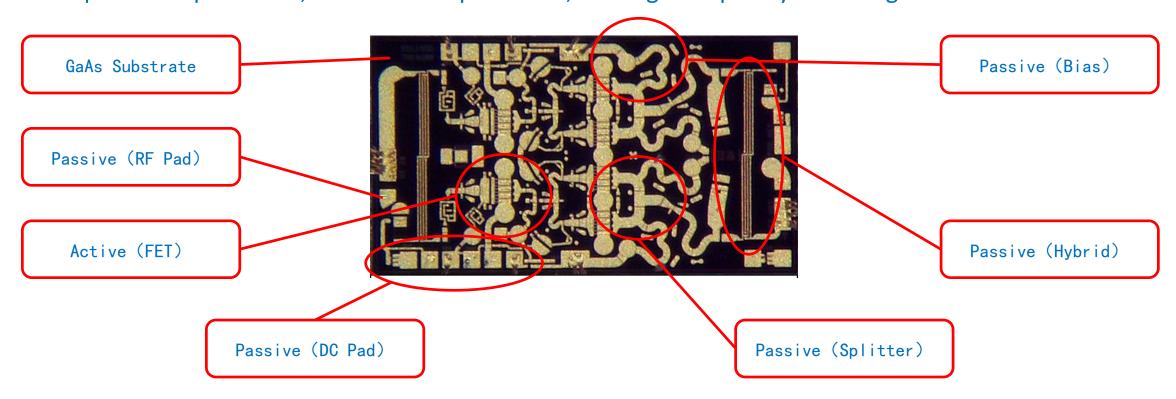
#### MMIC Measurement

Probe station, probes, calibration, automatic measurement.



#### Monolithic Microwave Integrated Circuits (MMIC)

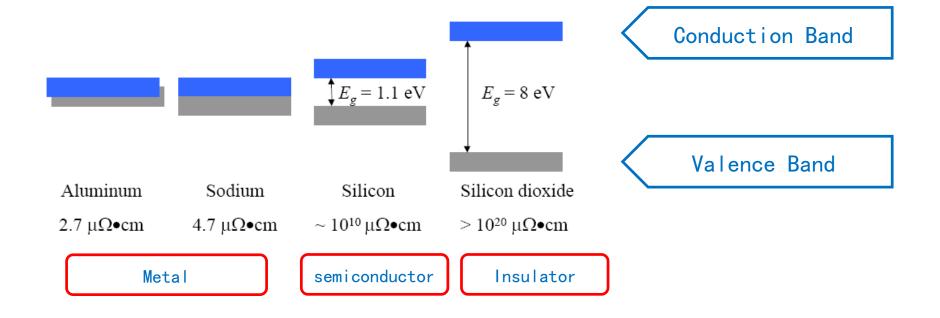
MMIC is a type of microwave integrated circuit that integrates active and passive circuits in single semiconductor substrate. These devices typically perform functions such as microwave mixing, power amplification, low-noise amplification, and high-frequency switching.





#### Semiconductor and variable conductivity

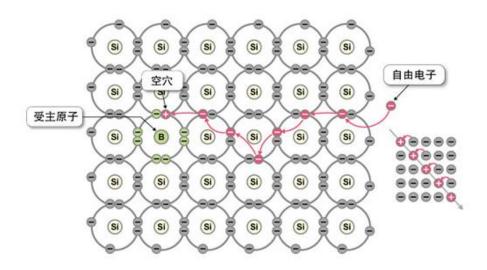
Semiconductors in their natural state are poor conductors because a current requires the flow of electrons, and semiconductors have their valence bands filled, preventing the entry flow of new electrons.

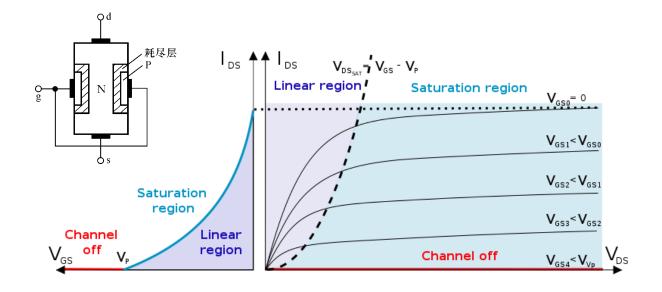




#### Semiconductor and variable conductivity

There are several developed techniques that allow semiconducting materials to behave like conducting materials, such as doping or gating.







### Semiconductor materials

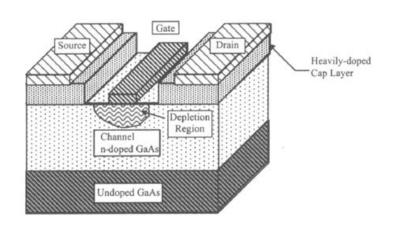
	G1	G	2	G3		
Parameters	Si	GaAs	InP	GaN	SiC	
Bandgap (eV)	1. 12	1. 42	1. 35	3. 4	3. 2	
Breakdown(MV/cm)	0. 38	0. 42	0. 5	3. 3	3	
Therm Cond(W/cm•k)	1. 4	0. 45	0. 68	3	4. 5	
Sat Velocity(10 <sup>7</sup> cm/s)	0. 7	2. 1	2. 3	2. 1	0. 2	
Mobility(cm <sup>2</sup> /vs)	1500	8500	5400	2000	1500	
Dielectric Const	11.8	12. 8	8	14	10	
Working Temp(°C)	200	350	300	600	800	
Rad Resistance(rad)	10 <sup>4</sup>	10 <sup>6</sup>	10 <sup>6</sup>	10 <sup>10</sup>	10 <sup>10</sup>	

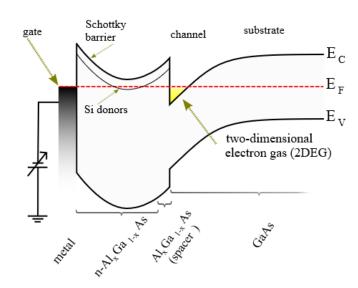


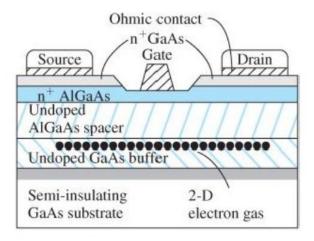
#### Heterojunction and HEMT

Heterojunctions occur when two differently doped semiconducting materials are joined together.

A High-electron-mobility transistor (HEMT) is a field-effect transistor incorporating a junction between two materials with different band gaps (i.e. a heterojunction) as the channel instead of a doped region (as is generally the case for MESFET).







**MESFET** 

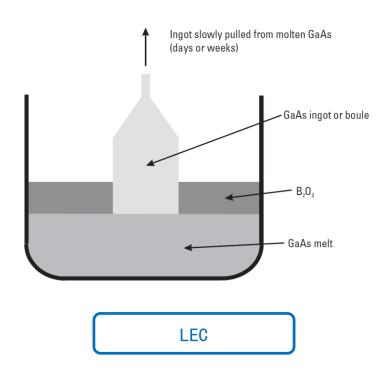
HEMT

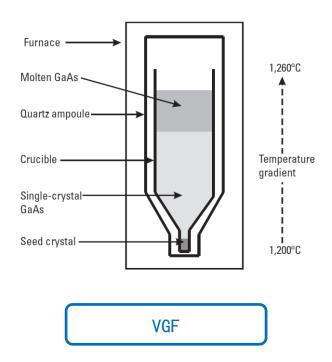


#### Substrate material growth

Single-crystal substrate growth techniques:

Liquid-Encapsulated Czochralski (LEC) and Vertical Gradient Freeze (VGF)





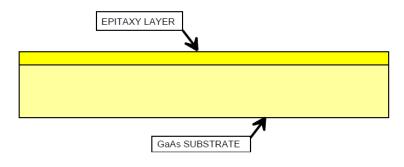


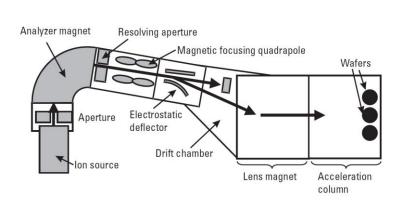




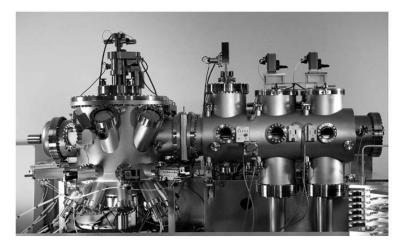
### Creating an active layer

There are three ways to make the semiconductor conducting on the wafer surface:









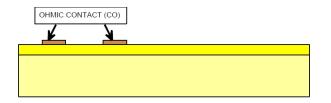
Molecular beam epitaxy (MBE)



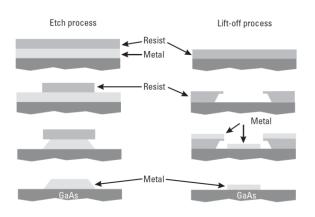
Metal-organic chemical vapor deposition (MOCVD)

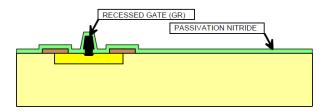


# Photolithography

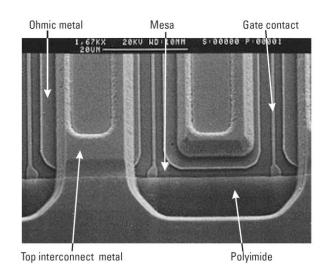


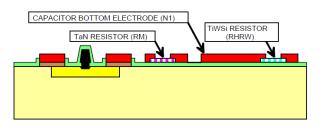
Ohmic Contact



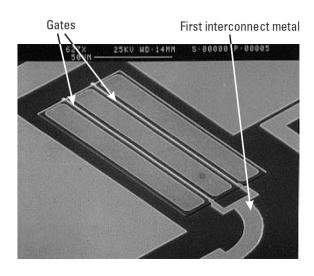


Gate Contact & Passivation



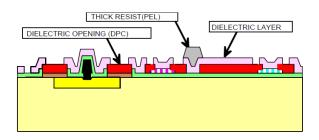


First & Resistive Metals

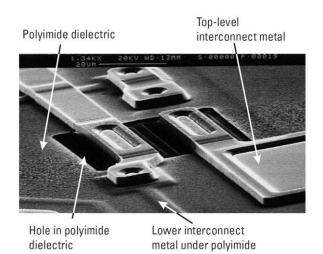


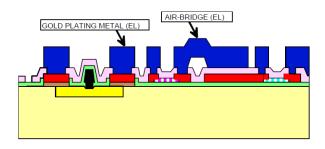


# Photolithography

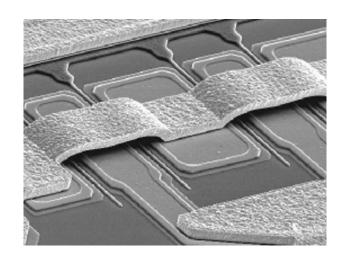


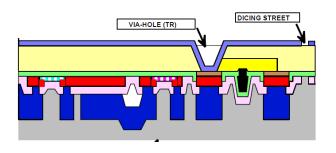
Dielectric Layers



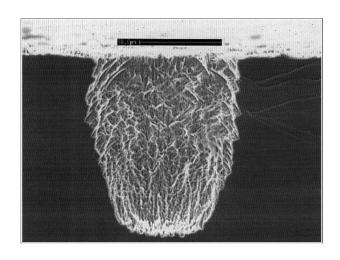


Top Metal & Air Bridge



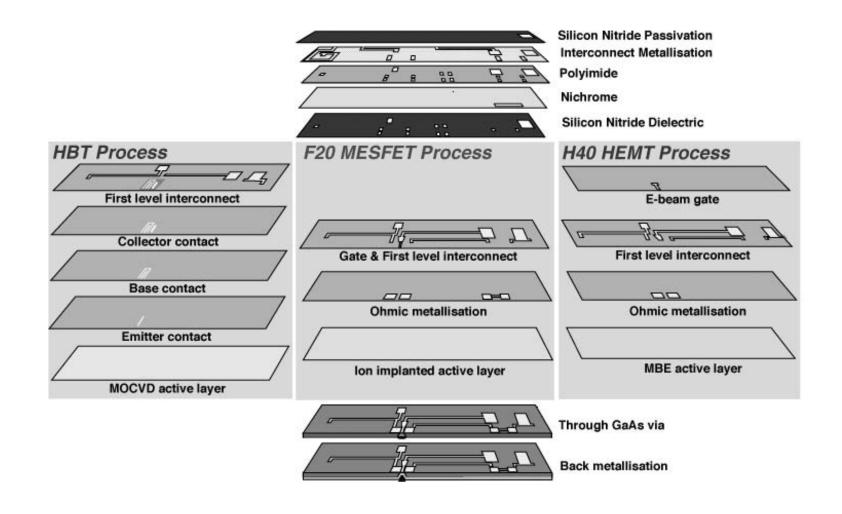


Thru-sub Via & Back Metal





### Typical MMIC process layers





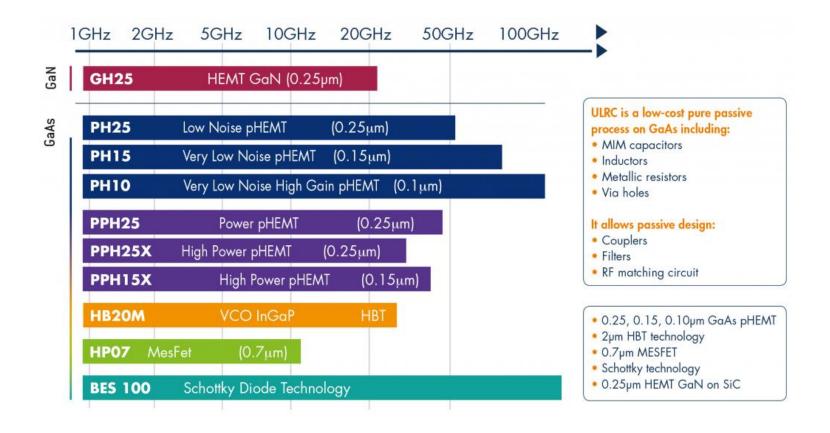
# Foundry Services (GaAs/GaN)





#### Foundry Services (GaAs/GaN)







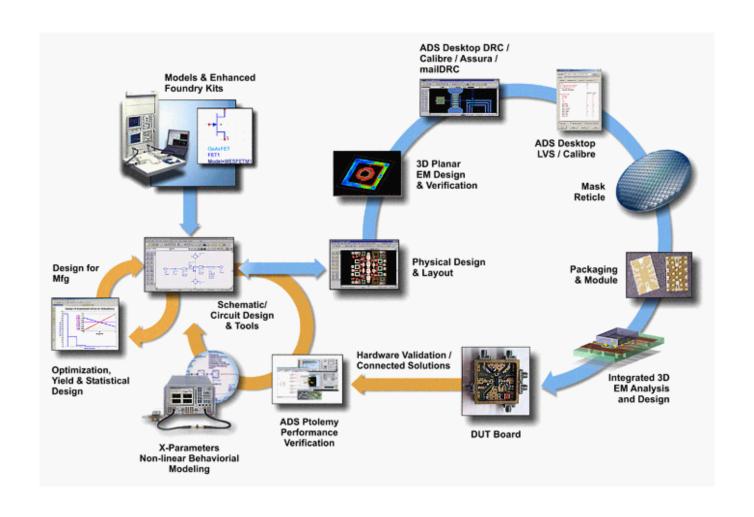
# Foundry Services (GaAs/GaN)



Process	<b>GH25</b> GaN	<b>PH25</b> Low Noise	PH15 Low Noise	PH10 Low Noise	PPH25 Power	PPH25X High Power	PPH15X High Power	HB20M VCO	HP07	BES
Active device	HEMT	pHEMT	pHEMT	pHEMT	pHEMT	рНЕМТ	рНЕМТ	НВТ	MESFET	Schottky
Power Density	4.5W/mm	250mW/mm	300mW/mm	250mW/mm	700mW/mm	900mW/mm	800mW/mm	2W/mm	400mW/mm	2
Gate Length	0.25µm	0.25µm	0.15µm	0.1µm	0.25µm	0.25 µm	0.15µm	2μm Emitter width	0.7µm	1µm
lds (gm max) lds sat/lc	750mA/mm 1000mA/mm	200mA/mm 500mA/mm	220mA/mm 550mA/mm	280mA/mm	200mA/mm 500mA/mm	170mA/mm 450mA/mm	350mA/mm 575mA/mm	0.3mA/µm²	300mA/mm 450mA/mm	34.5
V <sub>BOS</sub> / V <sub>BOX</sub>	>100V	> 6V	> 4.5V	> 5V	> 12V	> 18V	> 12V	> 14V	> 14V	< -5V (Anode/ Cathode
Cut off freq.	30GHz	90GHz	110GHz	130GHz	50GHz	45GHz	70GHz	30GHz	15GHz	3THz
Vpinch	-3.4V	- 0.8V	- 0.7V	-0.45V	- 0.9V	- 0.9V	- 0.95V	+	- 4.0V	
Gm max / β	300mS/mm	560mS/mm	640mS/mm	750mS/mm	450mS/mm	400mS/mm	480mS/mm	60	110mS/mm	
Noise / Gain	1.8dB/11dB @15GHz	0.6dB / 13dB @10GHz 2dB / 8dB @40GHz	0.5dB / 14dB @10GHz 1.9dB / 6dB @60GHz	2.3dB / 4.5dB @70GHz	0.6dB / 12dB @10GHz		1.8dB / 6dB @40GHz	8	٠	



# MMIC design procedure





#### MMIC design software

#### Cadence

Layout, LVS and DRC Check Circuit-Level Simulation

#### **ADS**

Circuit-Level and EM Simulation Layout, DRC Check

#### Ansoft HFSS

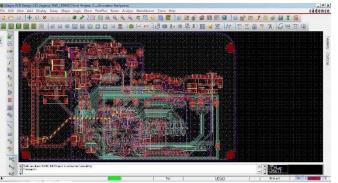
EM-Level Simulation

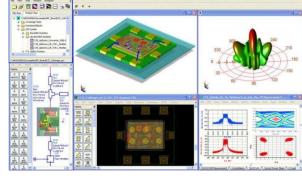
#### AWR Microwave Office

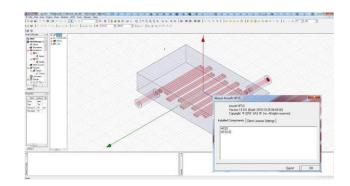
Circuit-Level and EM Simulation Layout, DRC Check

#### IC-CAP

Modelling Software



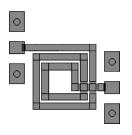


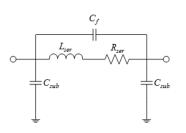


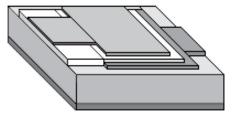


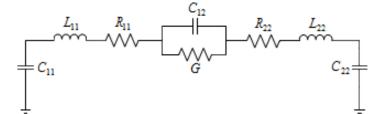


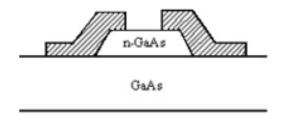
Passive device modeling (linear)

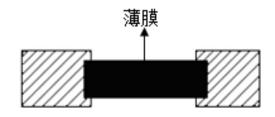


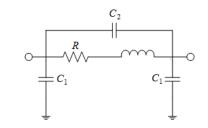


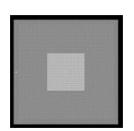


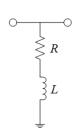






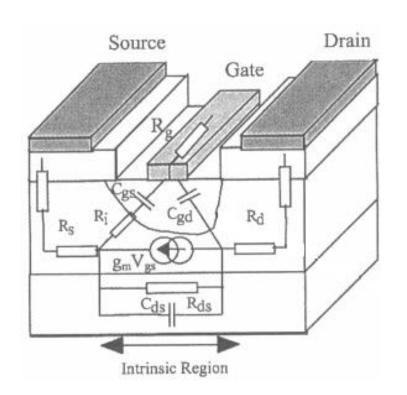


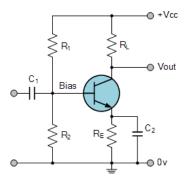


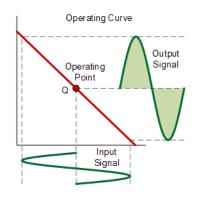


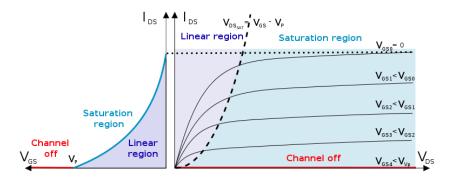


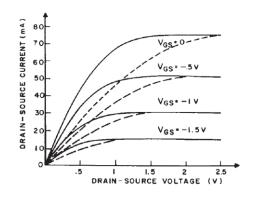
Active device modeling (non-linear)





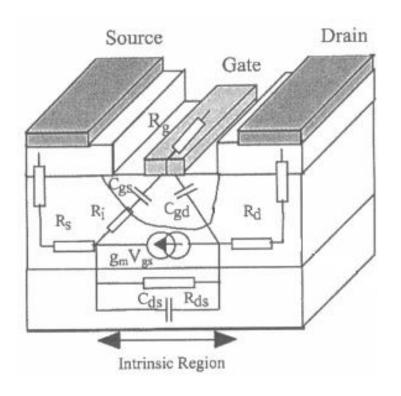








#### Modeling techniques

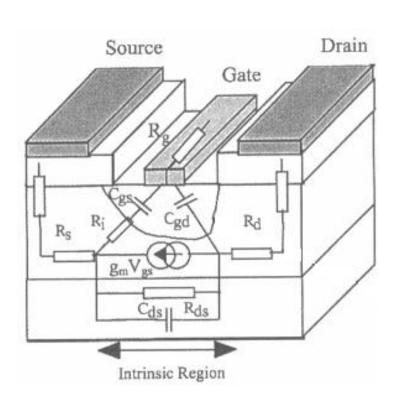


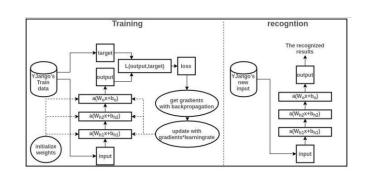
- ◆ Analytical Model
- ◆ Numerical Model
- ◆ Empirical Model

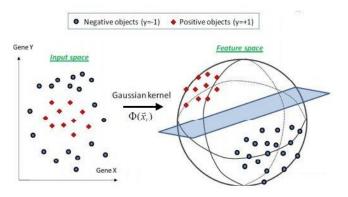
<u>Time</u>	Model Re	markable Contribution
1980 Curtice	Curtice Model	First Empirical Model
1987 Staz	Staz Model	2D Capacitance Model
1990 McCamant et al.	TOM	Negative DC Conductance
1991 Root	Root Model	First Table-based Model
1992 Angelov	Chalmers Model	Continuity to High Orders
1993 EESOF	EEFET/EEHEMT	RF Current Added
1997 Parker, Cojacoru	Parker Model/Corbra Model	Continuity to High Orders
1996-1997 Rolain, Wei	Black-box Models	General Device Modeling
1997- Wei	Enhanced TOM/AODM Models	Dispersion Handled Better
1997- Schreurs	Black-box Modeling	Time-domain
1999—Smiths	TOM3	

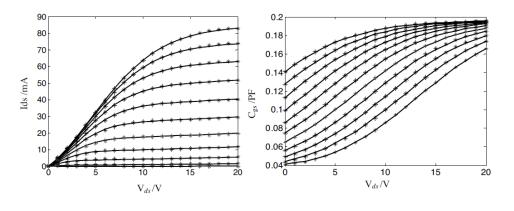


#### Modeling techniques – Empirical model





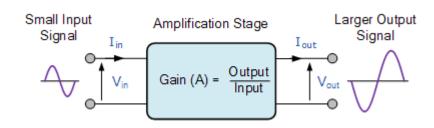


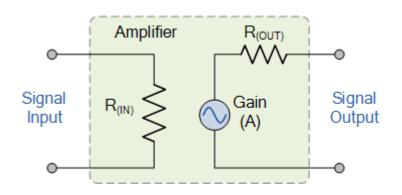




Amplifier is the generic term used to describe a circuit which increases its input signal, but not all amplifiers are the same as they are classified according to their circuit configurations and methods of operation.

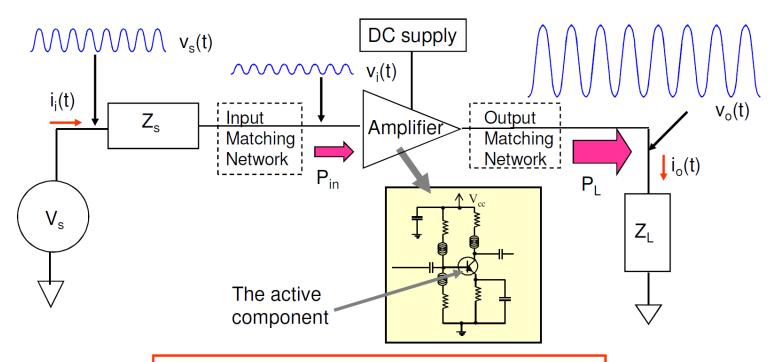
The difference between the input and output signals is known as the Gain of the amplifier and is basically a measure of how much an amplifier "amplifies" the input signal.







A general amplifier block diagram:



Input and output voltage relation of the amplifier can be modeled simply as:

$$v_o(t) = a_1 v_i(t) + a_2 v_i^{2}(t) + a_3 v_i^{3}(t) + H.O.T.$$



#### **Amplifier Classification**

#### According to signal level:

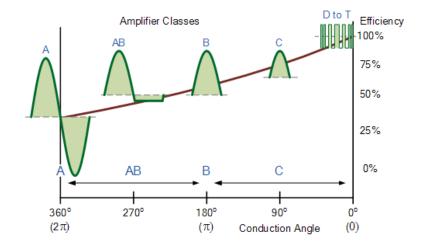
- Small-signal Amplifier.
- Power/Large-signal Amplifier.

#### According to D.C. biasing scheme of the active component:

Class A.
Class D.
Class B.
Class E.
Class F.

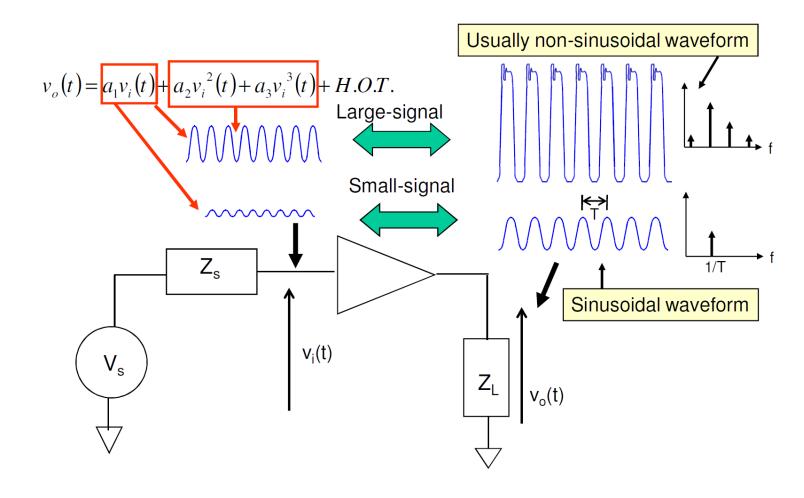
Class C.

Switch-Mode Amplifiers



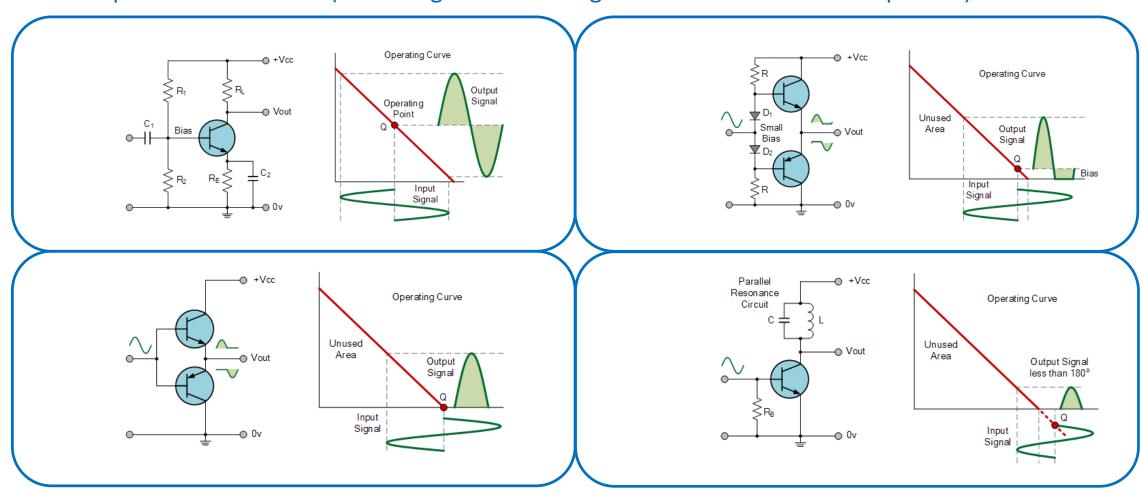


Amplifier Classification (Small Signal v.s. Large Signal Operation)





Amplifier Classification (according to D.C. biasing scheme of the active component)





#### Typical Microwave Amplifier Characteristics

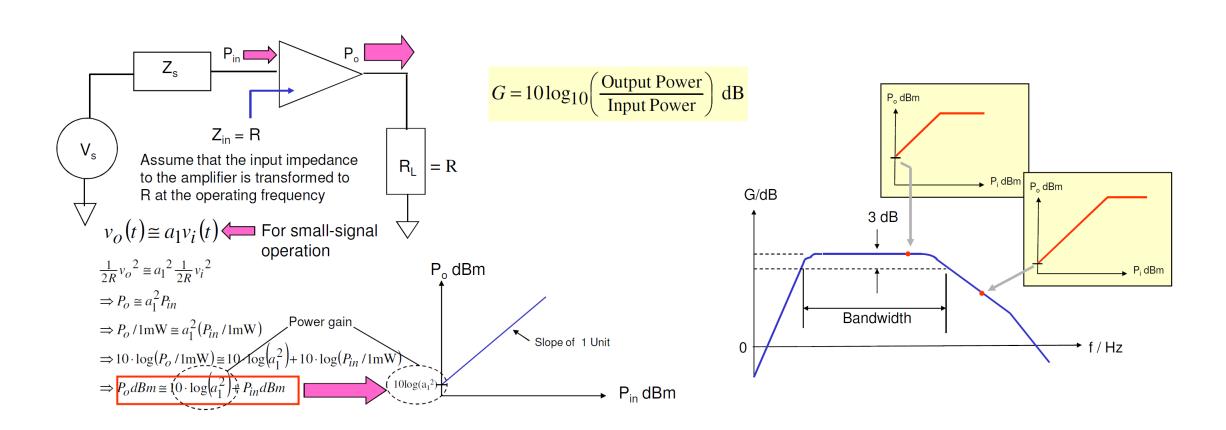
- 1. Power Gain.
- 2. Bandwidth (operating frequency range).
- 3. Noise Figure.
- 4. Phase response.
- 5. Gain compression.
- 6. Dynamic range.
- 7. Harmonic distortion.
- 8. Intermodulation distortion.
- 9. Third order intercept point (TOI).

Important to small-signal amplifier

Important parameters of large-signal amplifier (Related to Linearity)

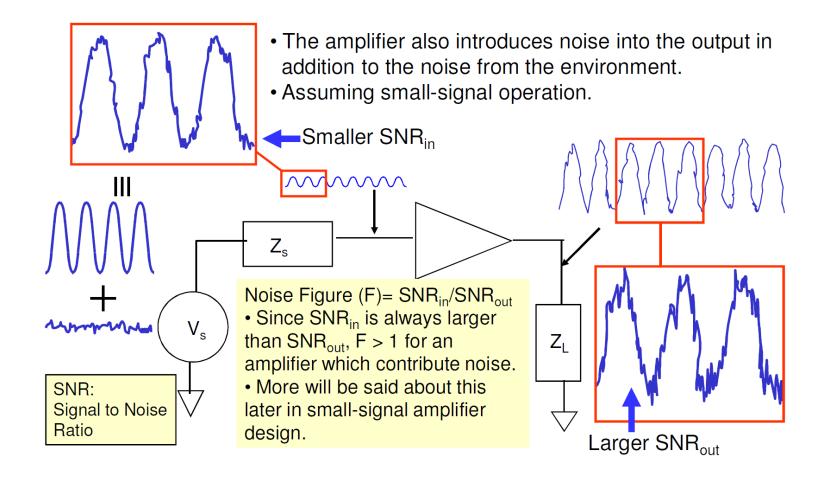


#### Power Gain & Bandwidth





#### Noise Figure

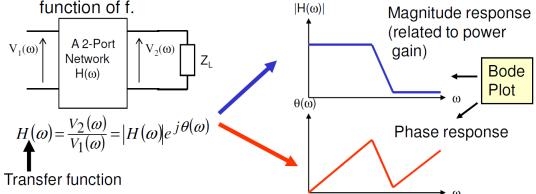




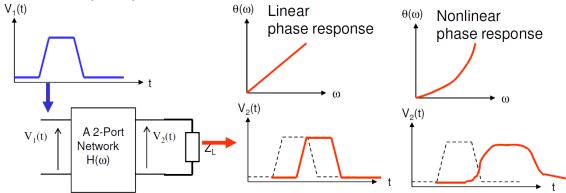
#### Phase Response

- Phase consideration is important for amplifier working with wideband signals.
- For a signal to be amplified with no distortion, 2 requirements are needed (from linear systems theory).
  - 1. The magnitude of the power gain transfer function must be a constant with respect to frequency f.

- 2. The phase of the power gain transfer function must be a linear function of f.  $|H(\omega)|$ Magnitude response

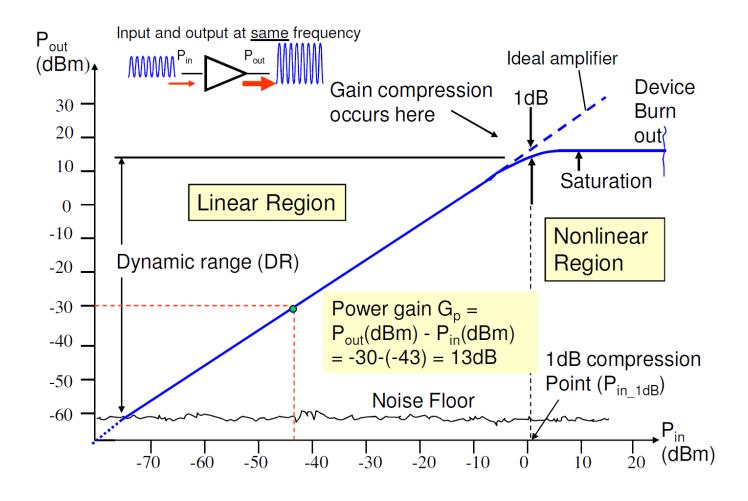


- A linear phase produces a constant time delay for all signal frequencies, and a nonlinear phase shift produces different time delay to different frequencies.
- Property (1) means that all frequency components will be amplified by similar amount, property (2) implies that all frequency components will be delayed by similar amount.





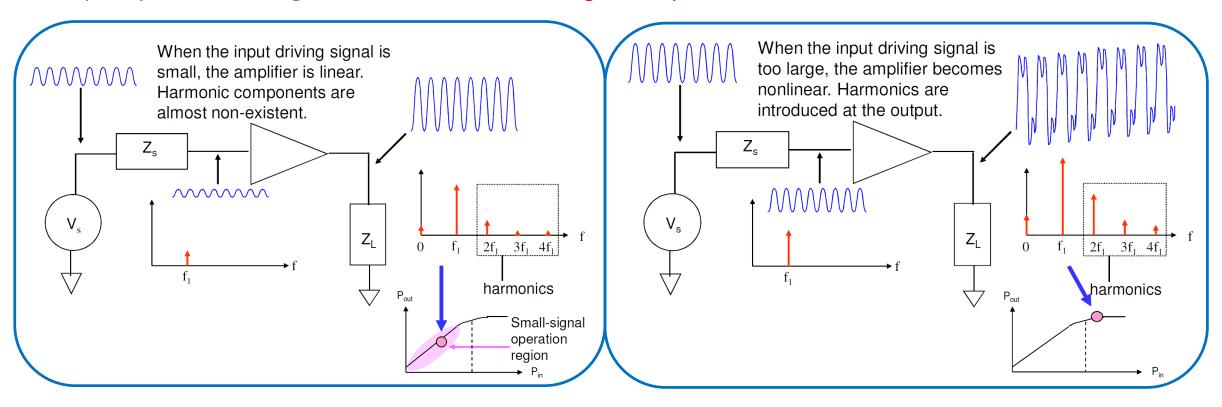
#### Dynamic Range and Gain Compression





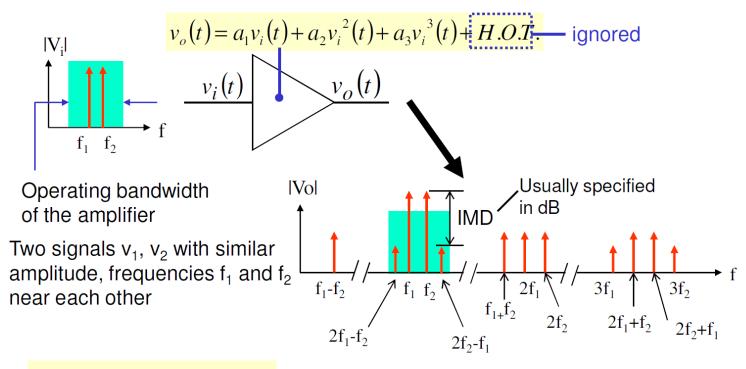
#### Harmonic Distortion

Harmonics generation reduces the gain of the amplifier, as some of the output power at the fundamental frequency is shifted to higher harmonics. This result in gain compression.





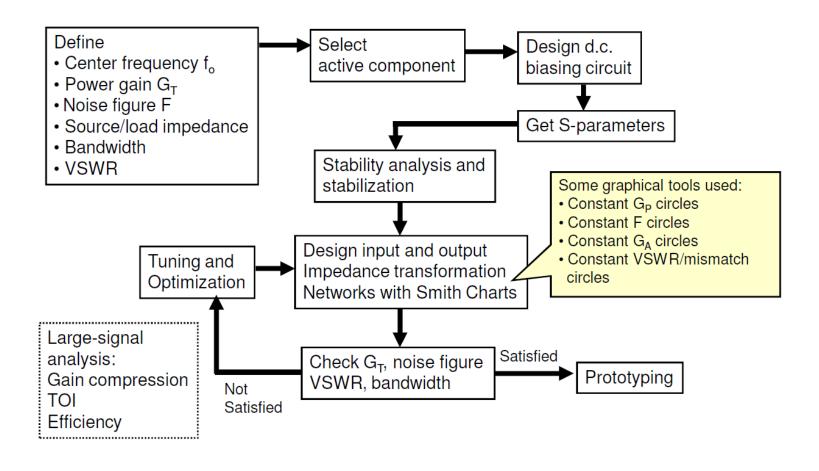
#### Intermodulation Distortion (IMD)



More will be said about this later in large signal amplifier design These are unwanted components, caused by the term  $\alpha_3 v_i^3(t)$ , which falls in the operating bandwidth of the amplifier.

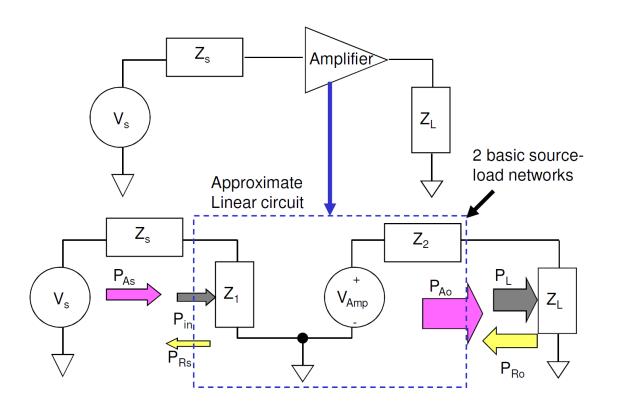


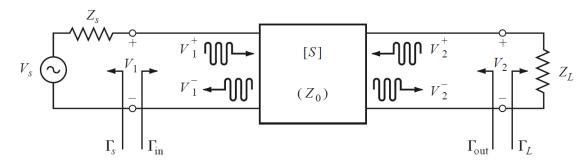
#### Small Signal Amplifier Design Flow





#### Two-port network analysis





Power Gain 
$$G_p = \frac{\text{Power delivered to load}}{\text{Input power to Amp.}} = \frac{P_L}{P_{in}}$$

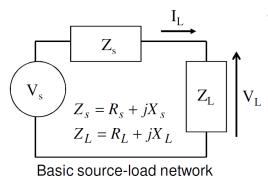
Available Power Gain  $G_A = \frac{\text{Available load Power}}{\text{Available Input power}} = \frac{P_{Ao}}{P_{As}}$ 

Transducer Gain  $G_T = \frac{\text{Power delivered to load}}{\text{Available Input power}} = \frac{P_L}{P_{As}}$ 

The effective power gain



#### Conjugate Matching: theory of maximum power transfer



We find that the value for  $R_1$  and  $X_1$ that would maximize  $P_L$  is

$$R_L = R_s$$
,  $X_L = -X_s$ .  
In other words:  $Z_L = Z_s^*$ 

Time averaged power dissipated across

 $P_L = \frac{1}{2} \text{Re} \{ V_L I_L^* \}$ 

$$V_L = \frac{V_s Z_L}{Z_s + Z_L} \qquad I_L = \frac{V_s}{Z_s + Z_L}$$

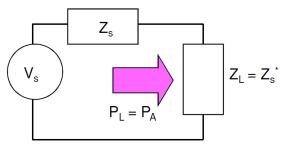
$$V_L = \frac{V_s Z_L}{Z_s + Z_L} \qquad I_L = \frac{V_s}{Z_s + Z_L}$$

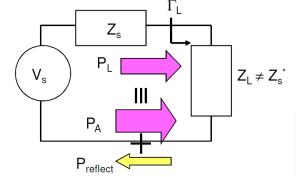
$$P_L = \frac{1}{2} \operatorname{Re} \left\{ \frac{V_s Z_L}{Z_s + Z_L} \cdot \left( \frac{V_s}{Z_s + Z_L} \right)^* \right\} = \frac{1}{2} \operatorname{Re} \left\{ \frac{|V_s|^2 Z_L}{|Z_s + Z_L|^2} \right\}$$

$$\Rightarrow P_L = \frac{1}{2} \frac{|V_s|^2 R_L}{(R_s + R_L)^2 + (X_s + X_L)^2}$$

$$P_L = P_L(R_L, X_L)$$

To maximize power transfer to the load impedance, Z<sub>1</sub> must be the complex conjugate of Z<sub>s</sub>, a notion known as Conjugate Matched.





Under conjugate match condition:

$$Z_L = Z_s^*$$
  $P_L(\max) = \frac{|V_s|^2}{8R_s} = P_A$  Available Power

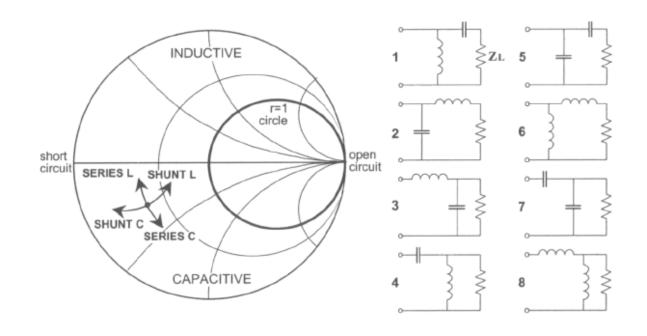
Under non-conjugate match condition:

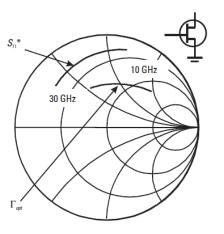
$$P_L < \frac{|V_S|^2}{8R_S} = P_A - P_{\text{Reflect}}$$
or  $P_L = P_A (1 - |\Gamma_L|^2)$ 

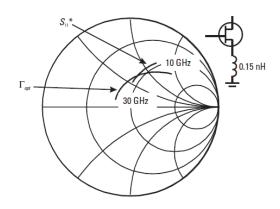
We can consider the load power P<sub>1</sub> to consist of the available power P<sub>A</sub> minus the reflected power P<sub>reflect</sub>.



I/O matching and series feedback

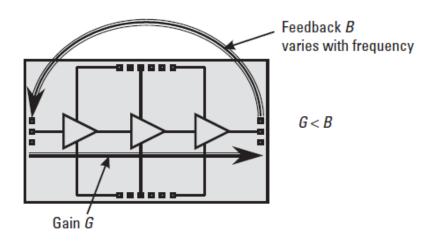






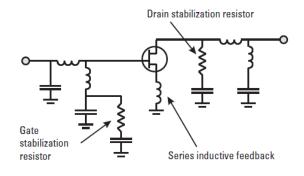


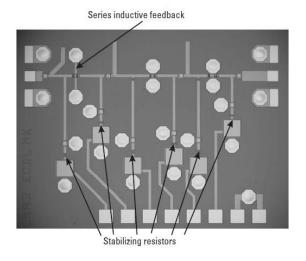
#### Stability design



- ◆ Gain < Backward isolation;
- ◆ Single-stage gain < 10dB.

$$K = \frac{1 - |S_{11}|^2 - |S_{22}|^2 + |\Delta|^2}{2|S_{12}S_{21}|} > 1$$







#### Example:

• Frequency:  $2\sim2.5\text{GHz}$ 

◆ Noise Figure: <1dB

◆ Gain: >20dB

◆ Power

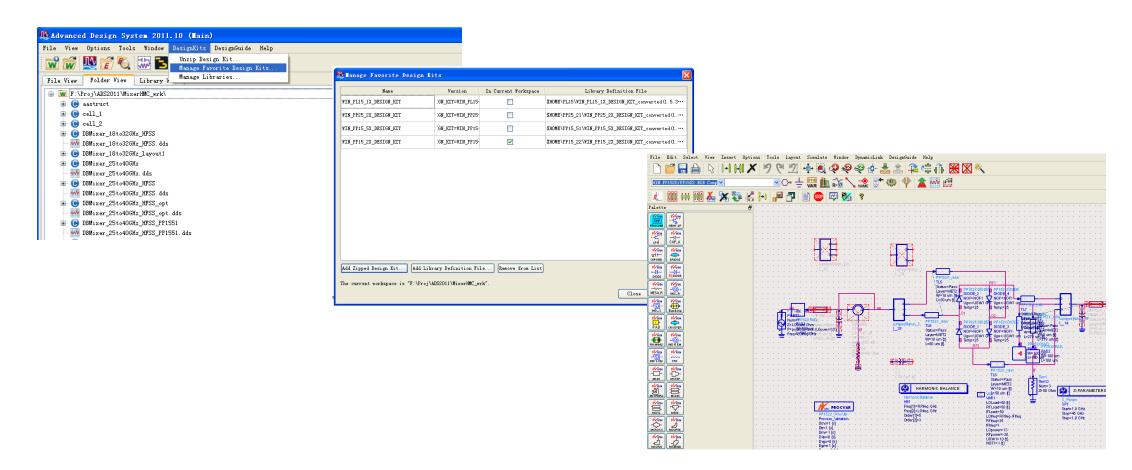
◆ consumption: 5V/55mA

◆ P-1: >10dbm

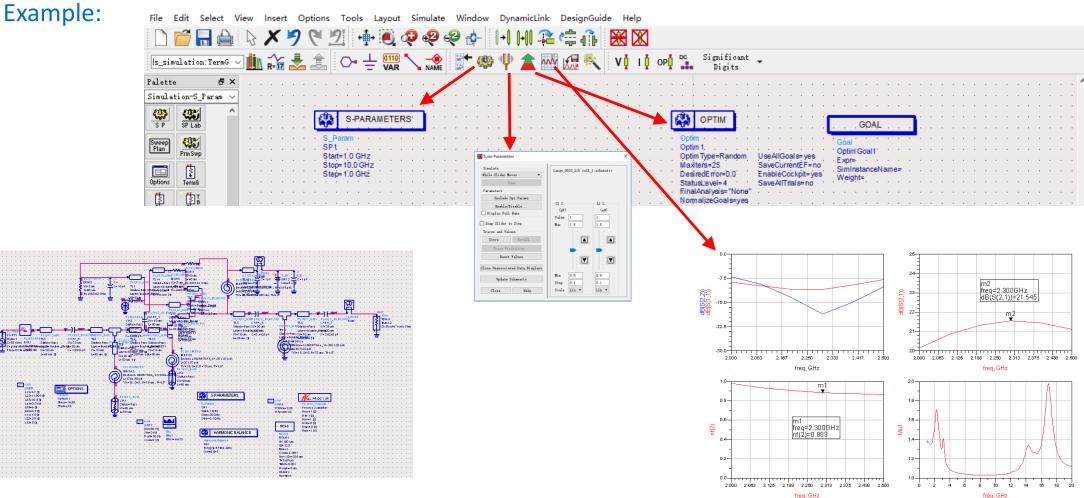
Process	PH25 Low Noise	PH15 Low Noise	PPH25 Power	PPH15 Power	HB20P Power	HP07 Power	BES
Active device	pHEMT	pHEMT	pHEMT	pHEMT	HBT	MESFET	Schottky
Power Density	250 mW/mm	300 mW/mm	700 mW/mm	600 mW/mm	3500 mW/mm	400mW/mm	
Gate Length	0.25 µm	0.15 µm	0.25 μm	0.15 µm	2 µm Emitter width	0.7 µm	1 µm
I <sub>DS</sub> (gm max) IDS SAT/I <sub>C</sub> HBT	200 mA/mm 500 mA/mm	220 mA/mm 550 mA/mm	200 mA/mm 500 mA/mm	300 mA/mm 600 mA/mm	0.3 mA/μm²	300 mA/mm 450 mA/mm	
V <sub>BDS</sub> / V <sub>BCE</sub>	> 6V	> 4.5V	> 12V	> 8V	> 16V	> 14V	< -5V (Anode/ Cathode
Cut off freq.	90 GHz	110 GHz	50 GHz	75 GHz	25 GHz	15 GHz	3 THz
Vpinch	- 0.8 V	- 0.7 V	- 0.9 V	- 0.9 V	122	- 4.0 V	-
Gm max/ β	560 mS/mm	640 mS/mm	450 mS/mm	550 mS/mm	70	110 mS/mm	
Noise / Gain	0.6dB / 13dB @10GHz 2dB / 8dB @40GHz	0.5dB / 14dB @10GHz 1.9dB / 6dB @60GHz	0.6dB/12dB @10GHz	1.6dB/7dB @40GHz		•	•



#### Example:

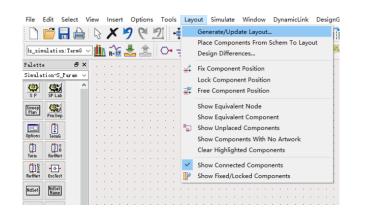




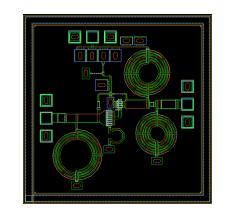




#### Example:











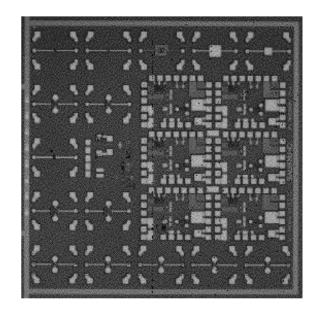
Generate layout

Layout & GDS file

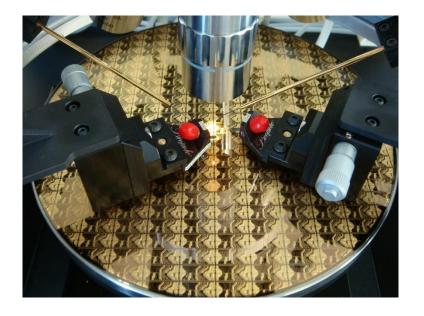
Foundry service



### PCM and RFOW



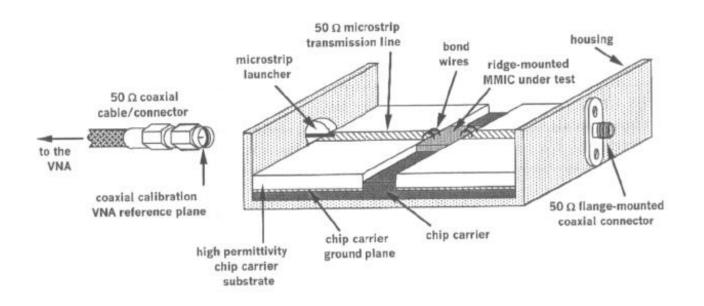
Process Control Monitoring (PCM)

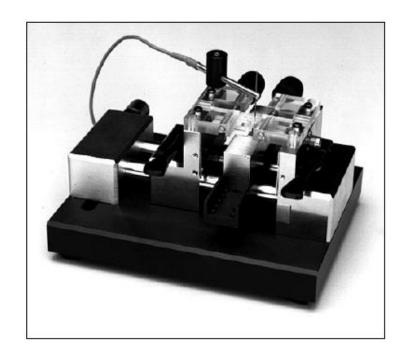


RF On-Wafer Measurement (RFOW)



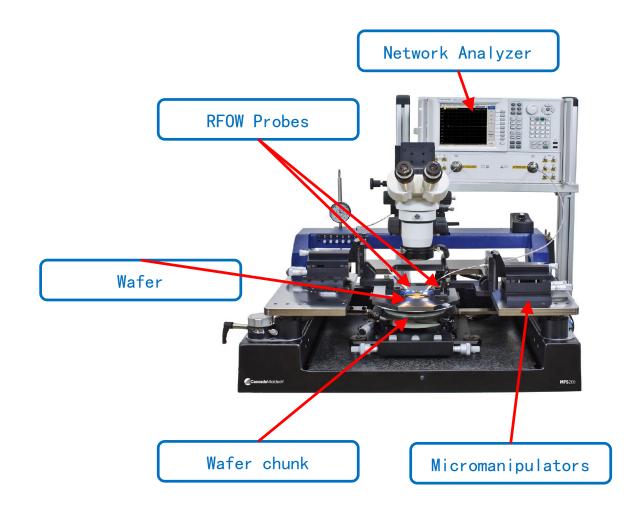
# Early On-Wafer-Measurement





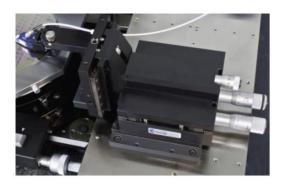


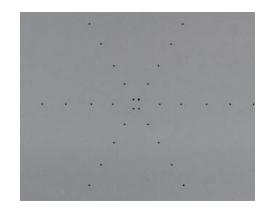
#### Probe Station





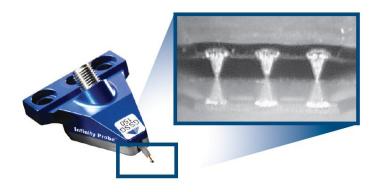




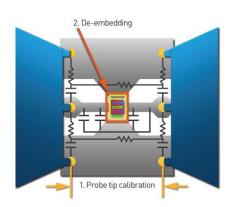




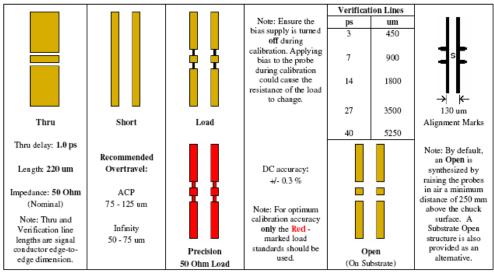
#### Probe and Calibration











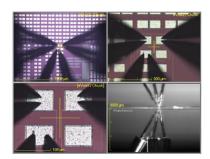


#### Automatic Measurement

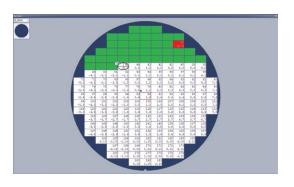




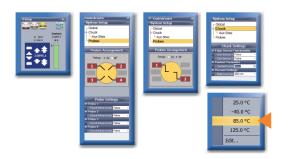
Alignment Tools



Probe Placement



Test Cycle Automation



Visual Reference Points



#### References

- Steve Marsh: **Practical MMIC Design**, Artech House, 2006.
- Jean-Luc Gautier: **Design of Microwave Active Devices**, ISTE Ltd., 2014.
- Leo G. Maloratsky: Integrated Microwave Front-Ends with Avionics Applications, Artech House, 2012.